

ABSTRACT

1
2 A detection / cleaning device for reticles employed in the production
3 of electronic components, wherein the detection / cleaning device
4 has a cleaning unit, in which a cleaning chamber is constructed. At
5 least one gas feed for introducing a pressurized fluid cleaning
6 medium opens into the cleaning chamber, and at least one suction
7 means, by means of which the gas can be discharged from the
8 cleaning chamber, leads from the cleaning chamber. The cleaning
9 chamber has at least one first opening for introducing and removing
10 a reticle. A detection unit for detecting contaminants on articles used
11 in semiconductor production is provided. The detection unit has a
12 detection means, into which a reticle can be introduced from one
13 feed side of the detection unit. The first opening of the cleaning
14 chamber and the feed side lie opposite each other. A feeding device
15 is provided for exchanging a reticle between the cleaning unit and
16 the detection unit.